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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

<u>In re</u> the application of)	
)	Examiner: Rachuba, Maurina
Xiuhua Zhang)	
)	Art Unit: 3723
Application No. 10/743,963)	
)	Docket No. LAM2P456
Filed: December 22, 2003)	
)	Date: August 24, 2005
For: CHEMICAL MECHANICAL PLANARIZATION)	
(CMP) SYSTEM AND METHOD FOR PREPARING)	
<u>A WAFER IN A CLEANING MODULE</u>)	

CERTIFICATE OF EXPRESS MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service on **August 24, 2005**, in an envelope as first class mail, addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed: *Cynthia Dawn*
Cynthia Dawn

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Restriction Requirement dated July 28, 2005, Applicants hereby elect, without traverse, Group III, Claims 13-21, to prosecute in the above-identified Patent Application.

Should the Examiner have any questions concerning this matter, the undersigned can be reached at the telephone number set out below.

Respectfully submitted,
MARTINE PENILLA & GENCARELLA, LLP

Michael L. Gencarella, Esq.
Reg. No. 44,703

710 Lakeway Drive, Suite 200
Sunnyvale, CA 94085
Telephone (408) 749-6900
Customer No. 25920

Attorney Docket No: LAM2P456